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ABSTRACT

A suction-and-holding face (14) for a component (1) in a suction nozzle (3) is formed from a semiconductor ceramic so that the suction-and-holding face to be brought into direct contact with the component in suction and holding has characteristics as semiconductor. Thus, detrimental effects due to occurrence of static electricity on the suction nozzle as well as detrimental effects due to an electrical conduction state between the suction nozzle and the component can be prevented from occurring.